



Document No.: 50090-250

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kimio HAGI, et al.

Application No.: 09/732,891

Group Art Unit: 2836

Filed: December 11, 2000

Examiner: Isabel Rodriguez

For: ELECTROSTATIC CHUCKING SYSTEM, AND APPARATUS AND
METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE
USING THE ELECTROSTATIC CHUCKING SYSTEM

5/A
F. BELL
12.26.02
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AMENDMENT

Box Non-Fee Amendment
The Commissioner for Patents and Trademarks
Washington, DC 20231

Sir:

The following Amendment and Remarks are submitted in response to the Office Action dated September 24, 2002. Please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel claim 1 in its entirety without prejudice or disclaimer of the subject matter and amend claims 2-8 as follows:

2. (Amended) The electrostatic chucking system according to claim 6, further comprising a temperature sensor for detecting the temperature of the semiconductor substrate held by said electrostatic chuck, wherein a signal output from said temperature sensor is input to said voltage control section to thereby control the applied voltage.

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